

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Filing Date . . . . . September 1, 1999  
Inventor . . . . . Weimin Li et al.  
Assignee . . . . . Micron Technology, Inc.  
Group Art Unit . . . . . 2822  
Examiner . . . . . T. Thomas  
Attorney Docket No. . . . . MI22-1208  
Title: Low K Interlevel Dielectric Layer Fabrication Methods



10/ Suppl.  
I.S.S.

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

G. Stanley  
5-31-01

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the documents listed on the accompanying PTO-1449 are enclosed. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 5-22-01

By:   
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